

Construction of the second 500 kV Photocathode DC-gun at KEK

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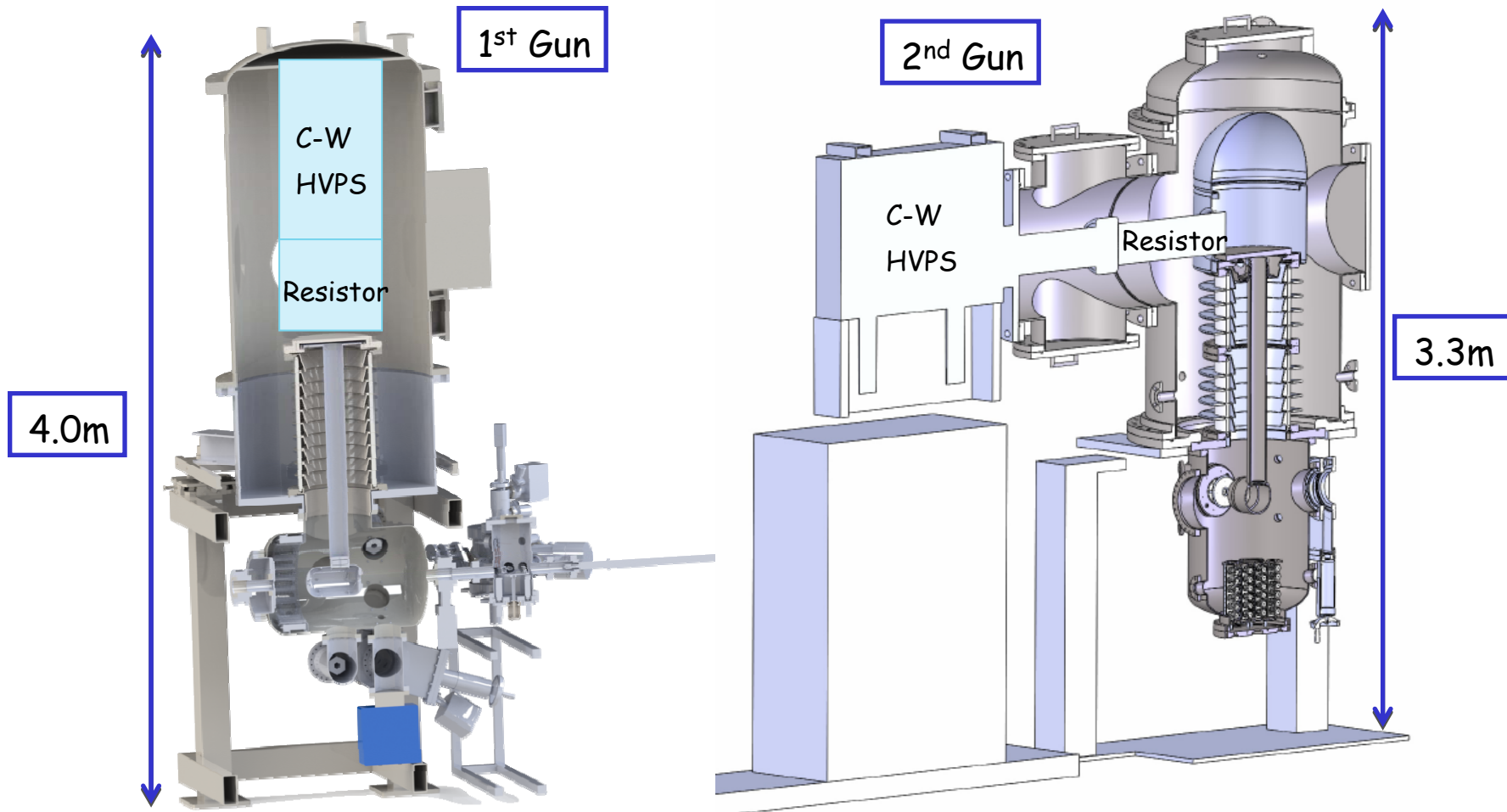
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Outline

- Introduction
- HV system setup & HV conditioning result
- Simultaneous triplet cathodes preparation system
- Summary

The 1st and 2nd 500kV DC Guns



Developed at JAEA from 2007 ~
Installed cERL at Oct. 2012.

Developed at KEK from 2009 ~

Special items of the 2nd DC-Gun

High voltage insulator

- 2 pairs of 5 segmented insulator
- Special Al_2O_3 based material (TA010, Kyocera)

Low outgassing vacuum system

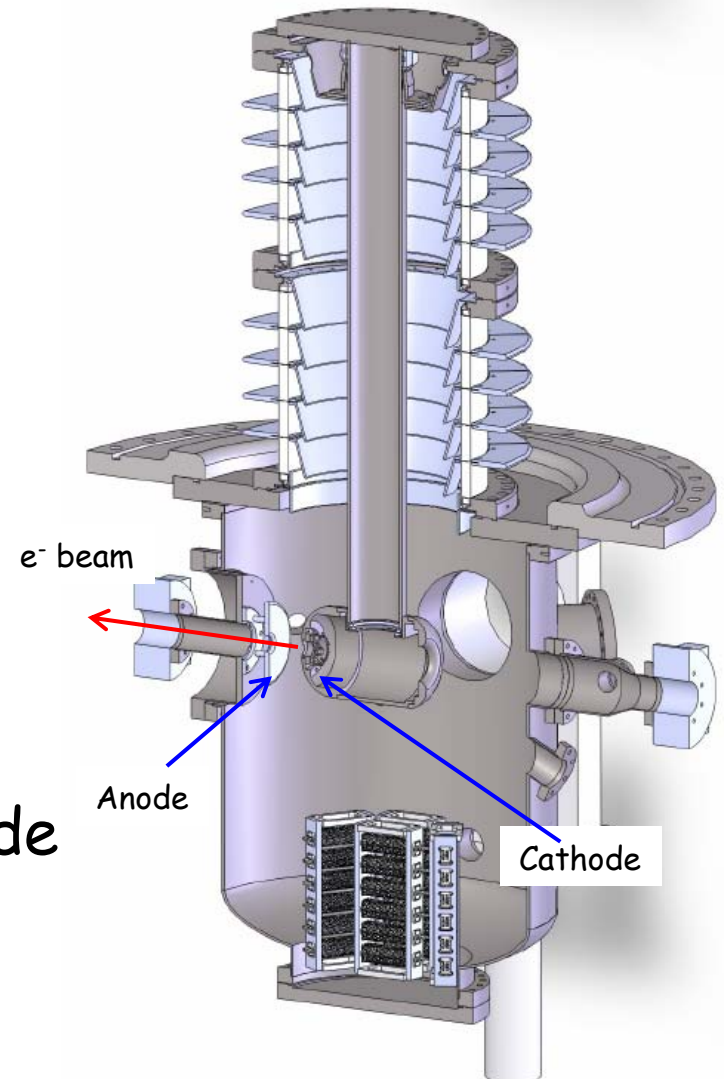
- Titanium chamber
- Titanium electrodes & guard rings
 - Non welding parts for in-vacuum components

High performance pumps for XHV

- 4K Bakeable cryopump & NEG pumps

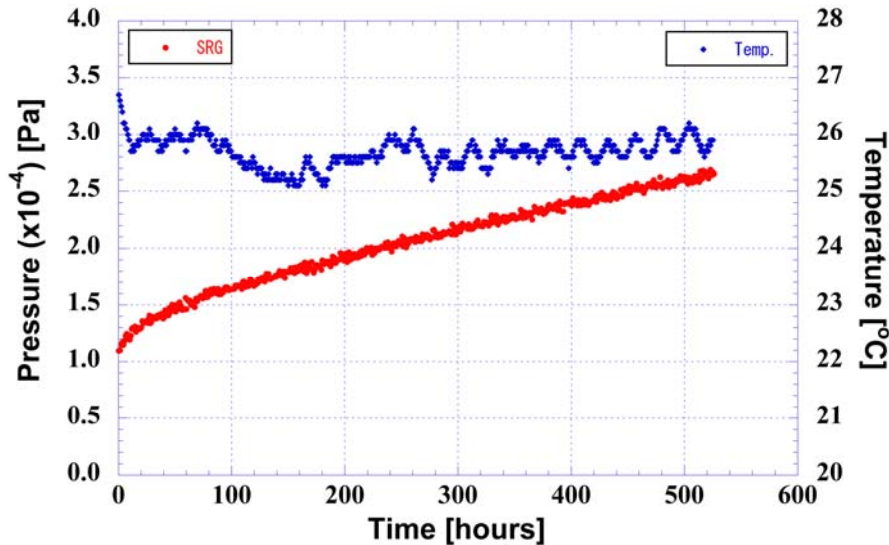
Isolated anode & Repeller electrode

- Dark current monitor
- Reducing low energy backward ions



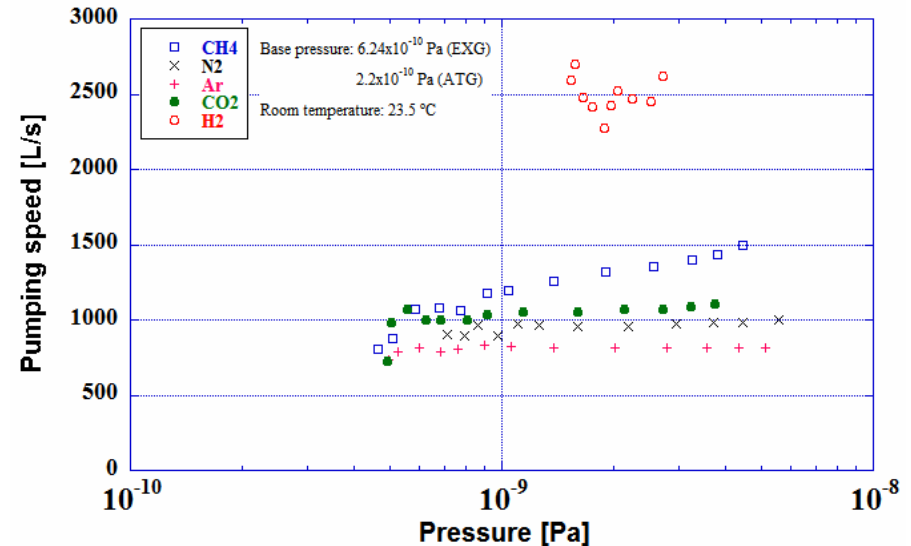
Vacuum performance

■ Outgassing rate



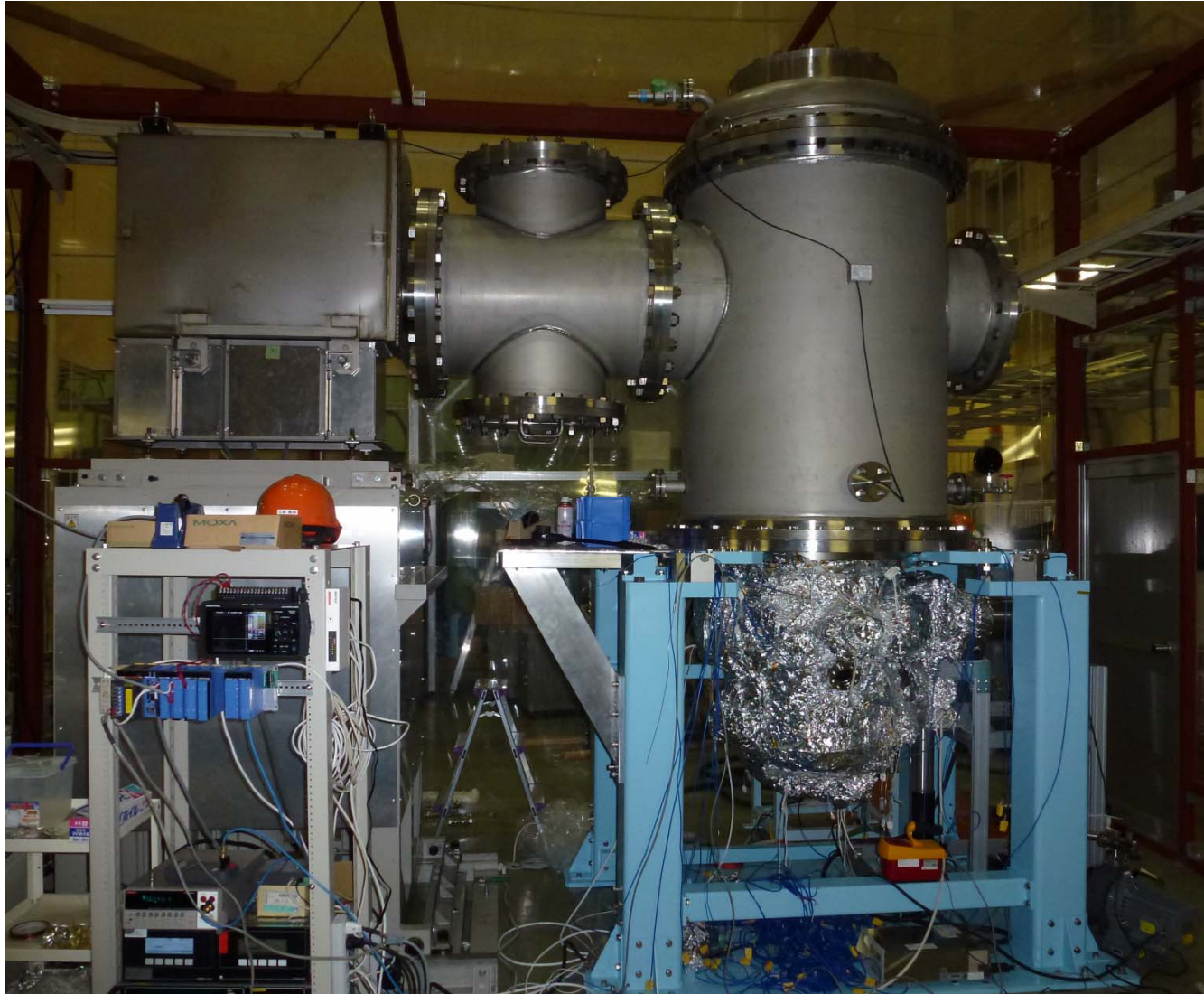
- ✓ All components except main pumps (cryopump & NEG) were installed.
- ✓ Very low total outgassing rate of 8.1×10^{-11} [Pa m³/s] (H₂ equivalent) was achieved.

■ Pumping speed of Bakeable cryopump

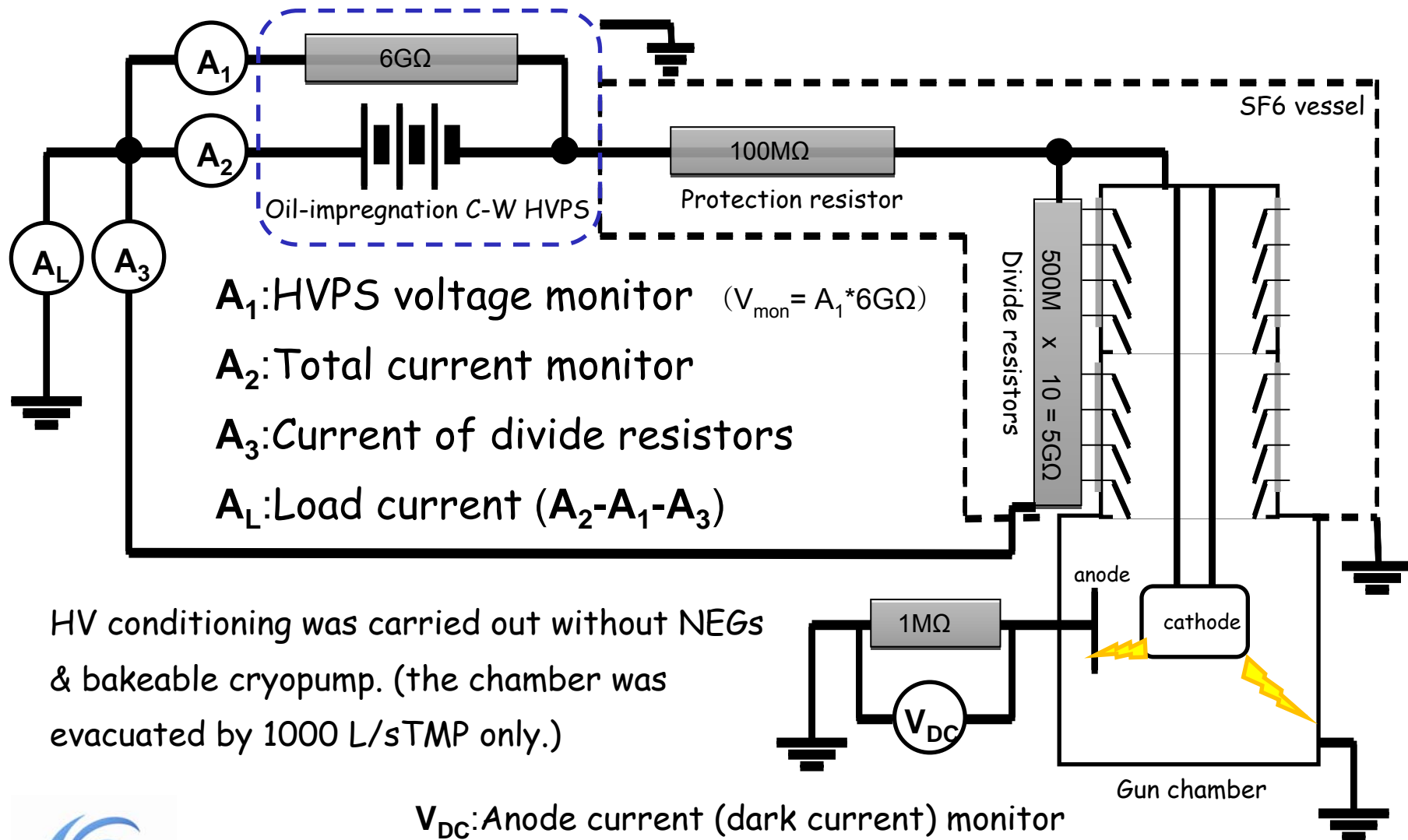


- ✓ Cryo-panel temperature: 4K
- ✓ High pumping speed was obtained for CH₄, N₂, Ar, CO₂ under XHV condition.
- ✓ Ultimate pressure was limited by adsorption equilibrium of adsorbent for hydrogen.

The 2nd 500kV DC-Gun @KEK

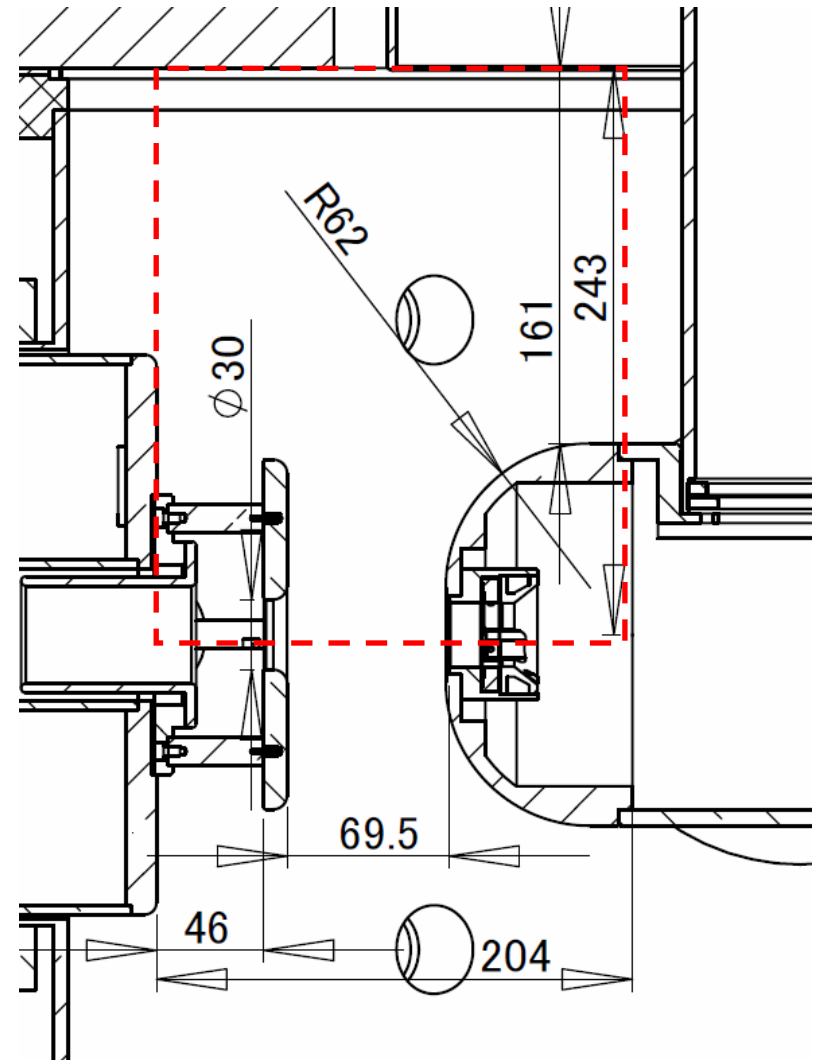
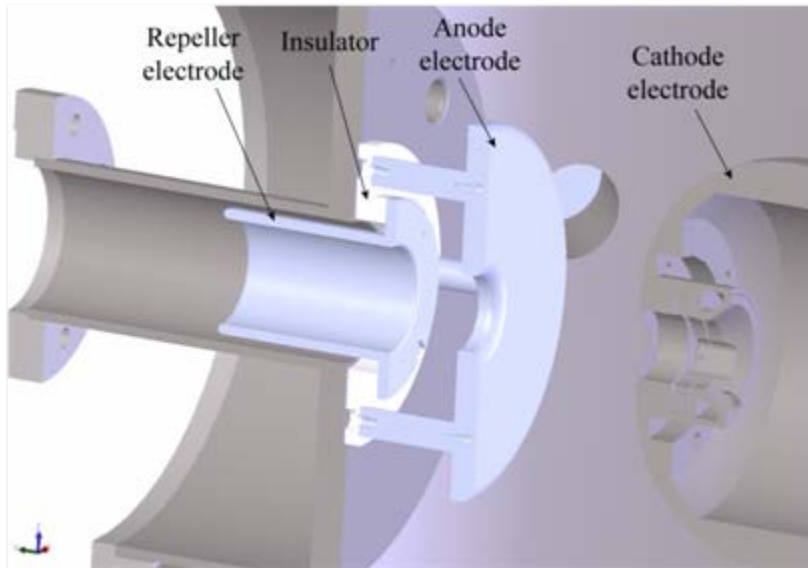


Outline of HVPS Connection



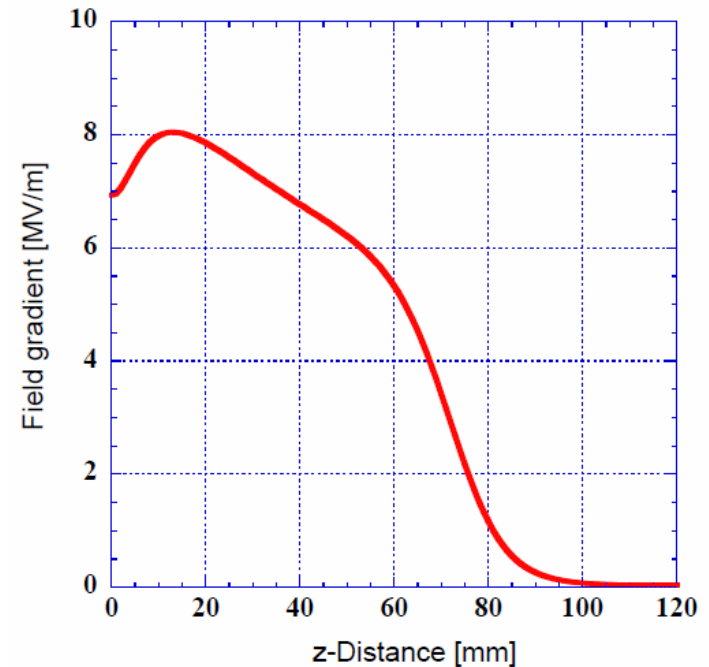
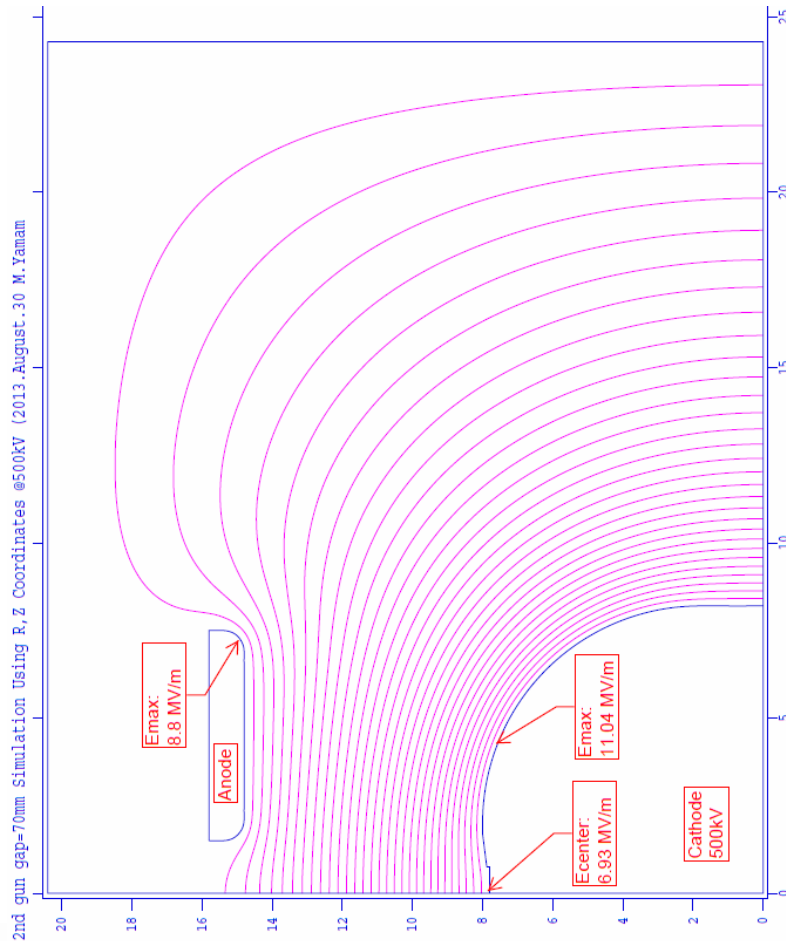
HV conditioning was carried out without NEGs & bakeable cryopump. (the chamber was evacuated by 1000 L/sTMP only.)

Electrodes Shape and Geometry



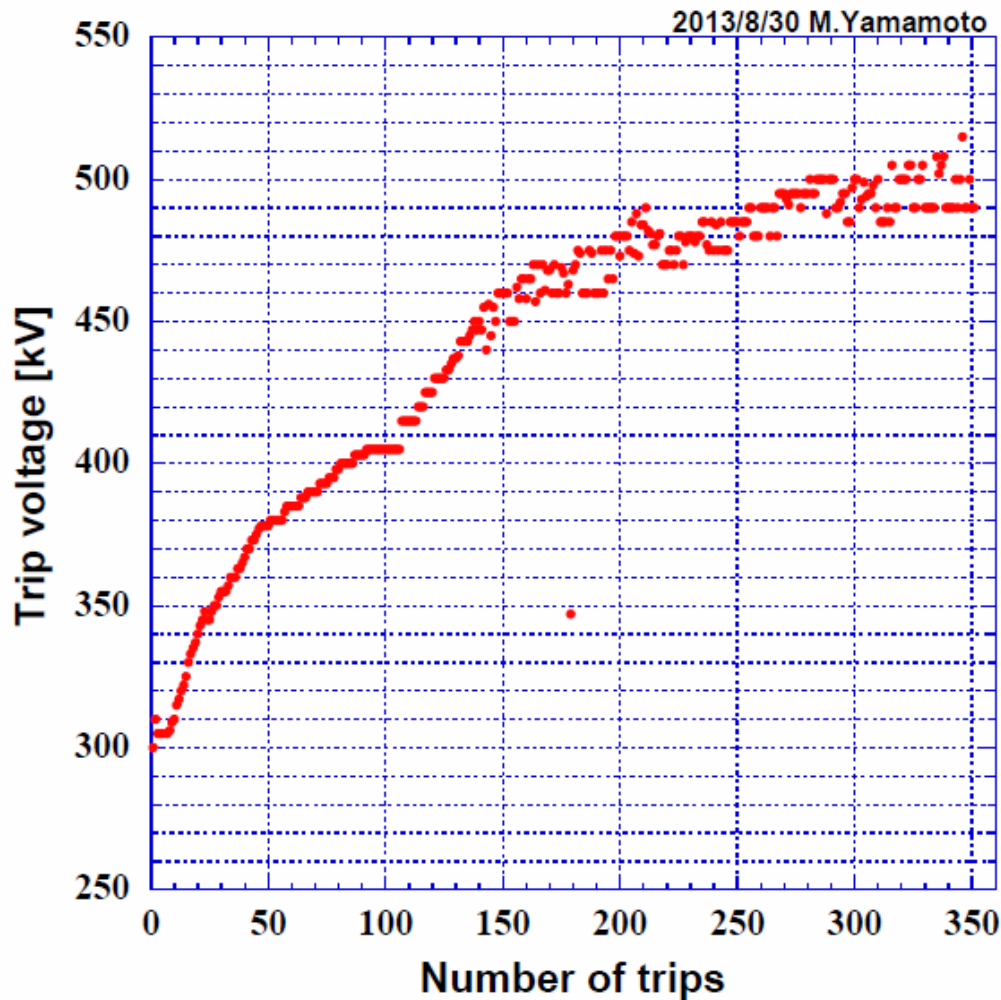
E-Field Map

E-Field Map @ 500 kV



- Cathode center: 6.9 MV/m
- Cathode electrode:
 - Outer surface: 11.0 MV/m (max.)
 - Edge of wehnelt: 11.9 MV/m (max.)
- Anode electrode: 8.8 MV/m (max.)

HV Conditioning History



- ✓ Base pressure: 1.0×10^{-8} Pa.
- ✓ SF_6 pressure: +0.2 MPa.
- ✓ Only 5 days conditioning.
(Just start from Aug.26th)
- ✓ The first trip happened at 300 kV.
- ✓ All trips involved vacuum trip and almost detected radiation.
- ✓ Trip voltage slope to be gentle around 500 kV.

Safety Interlock

Monitors for Safty

- * Vacuum (EXG, 3BG)
(trigger level: $>5 \times 10^{-7}$ Pa)
- * Radiation (Ionization chamber)
(trigger level: >20 uSv/h)
- * Anode current
(trigger level: >500 nA)

HVPS Controller

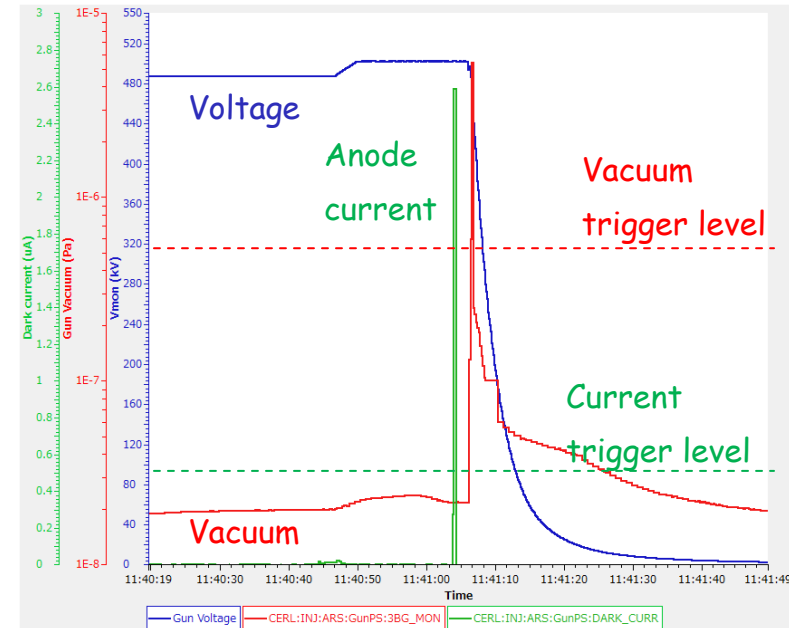
- * Over Current
(Total Current max.: 300uA)
- * Current Continuous mode > 1 s
(Load Current setting: 20uA)
- * Other troubles

Total Trips

351 times

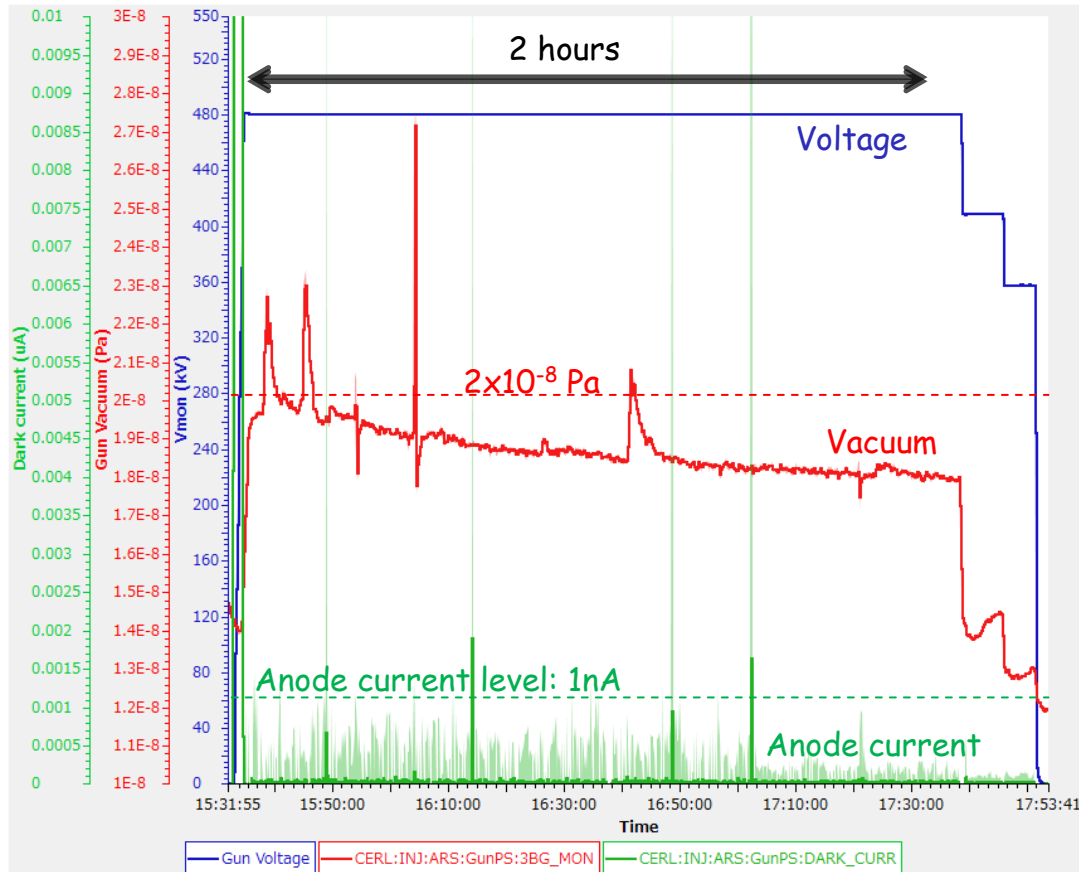
314 times

37 times



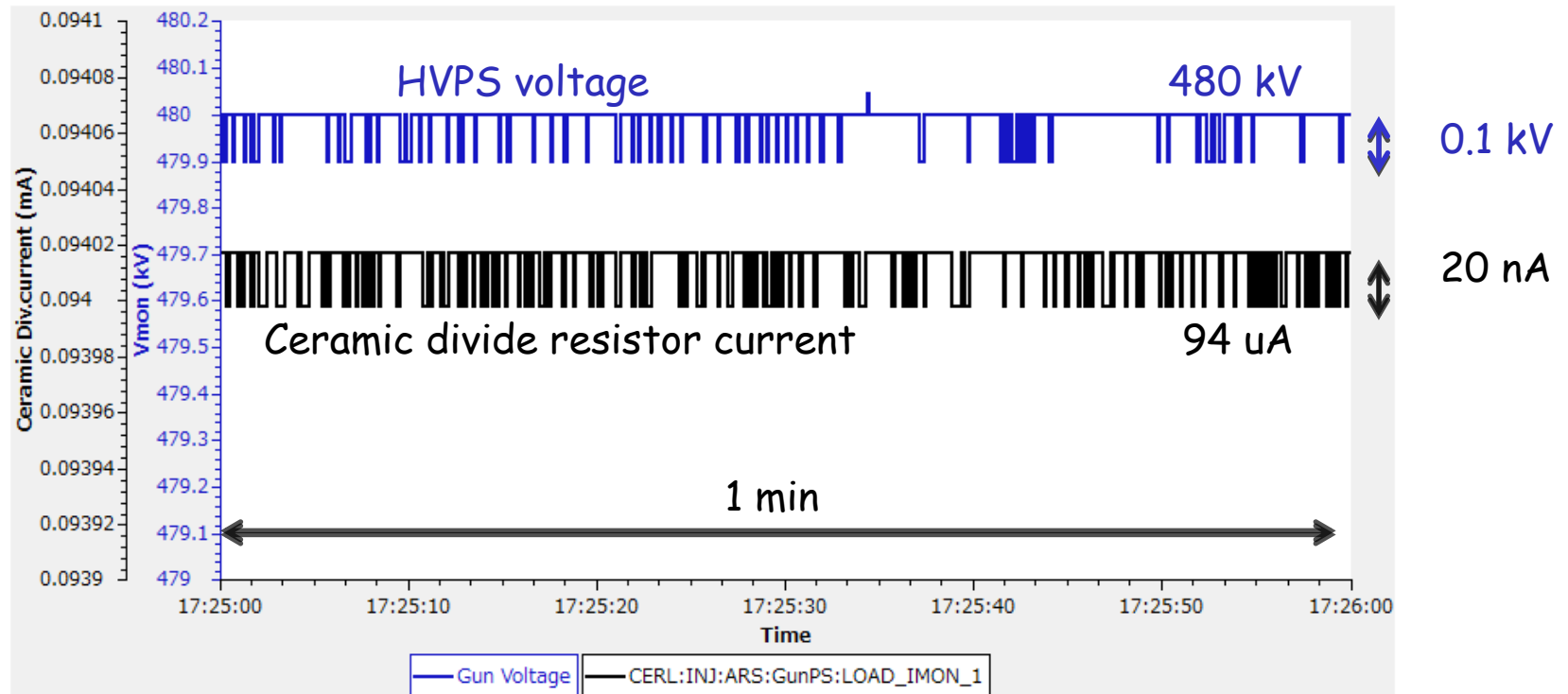
- ✓ ~90% trips happened between anode-cathode gap.
- ✓ Anode current monitor was helpful to reduce X-ray dose because of its quick response.

480 kV Test



- ✓ The test was carried out after HV conditioning of 350 trips.
- ✓ HV down didn't happen during 2 hours operation.
- ✓ Some small vacuum trips still remained.
- ✓ Anode current was lower than 1nA normally.
- ✓ Dependence of base pressure on applied voltage was observed.

HVPS Stability (without beam loading)

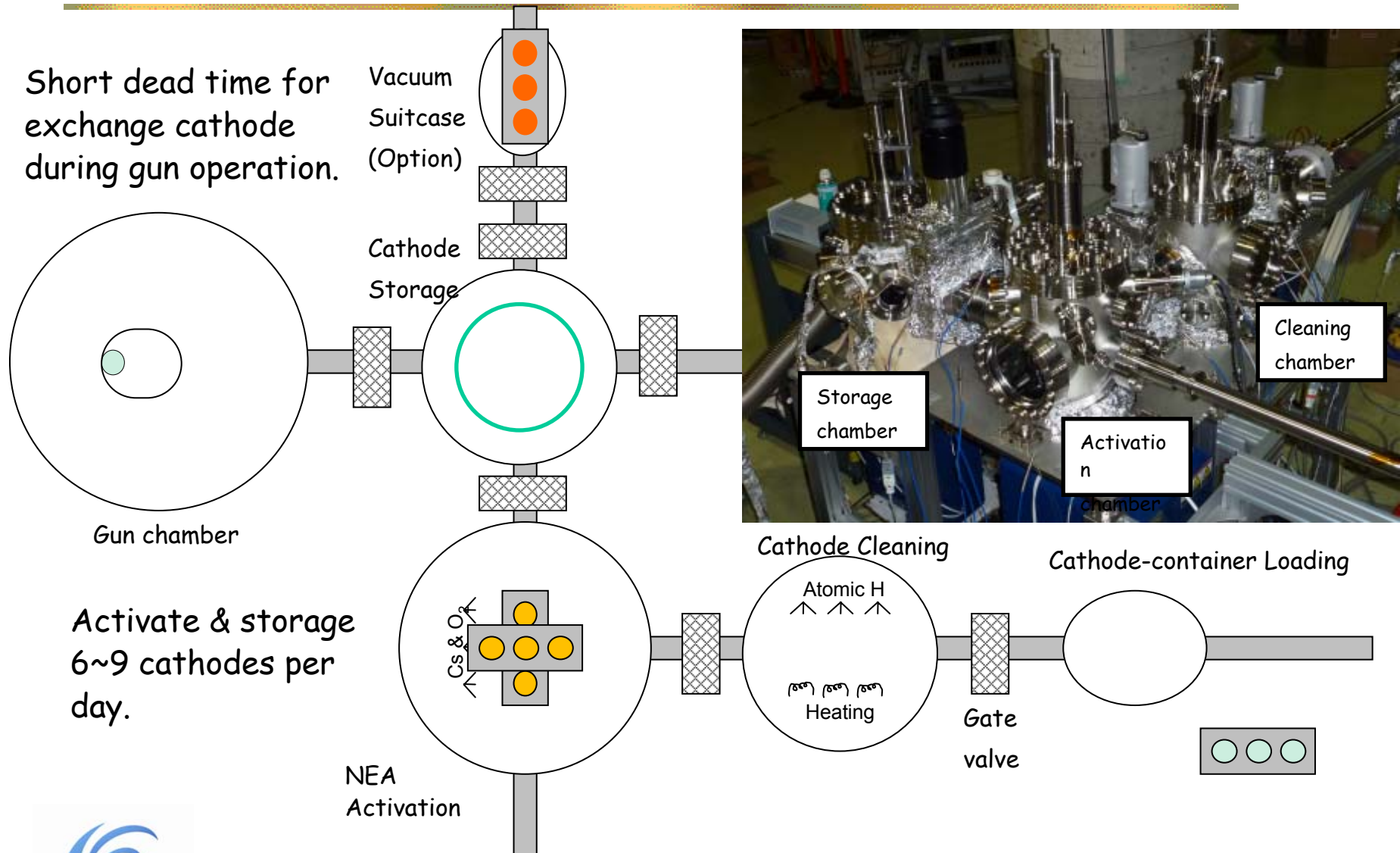


- ✓ About 1.5 hours need to stabilize HVPS output.
 - ✓ Less than 2×10^{-4} stability was obtained by HVPS voltmeter and ceramic divide resistor current independently.
- (Resolution was limited by 12-bit ADC of HVPS control PLC)

Cathode Preparation System (1)

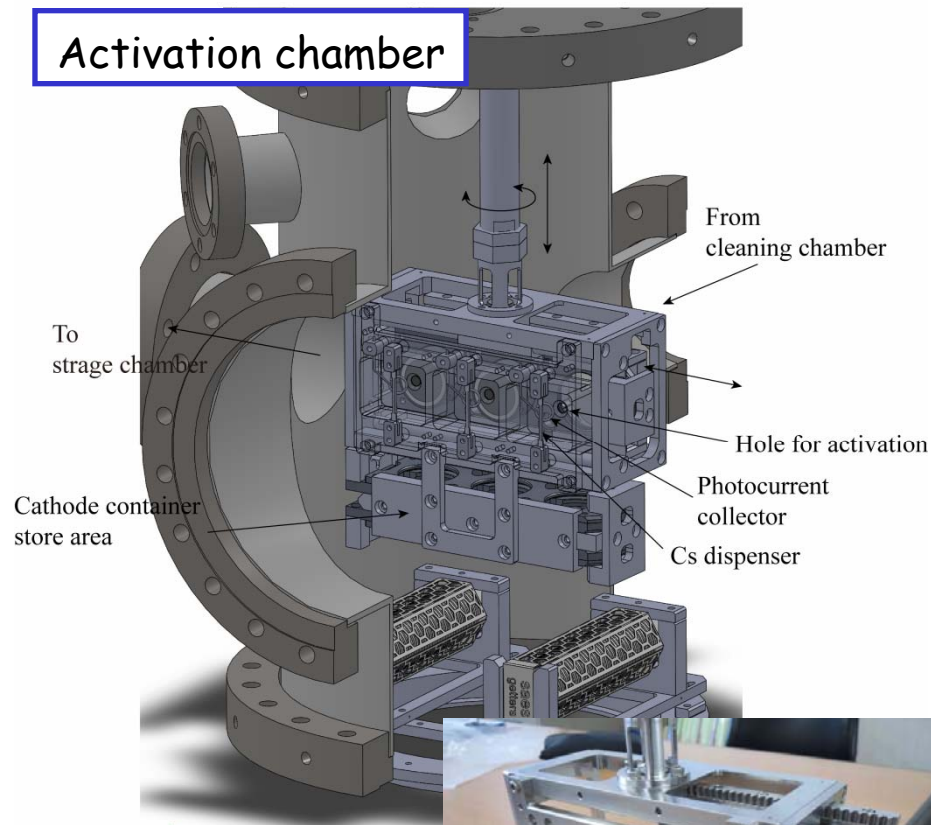
- ✓ NEA cathode is good for generate beam with low MTE. 😊
- ✓ NEA surface is easily damaged. 😞
 - Weak for ion back-bombardment.
 - Quite sensitive for vacuum. (It is difficult to treat by vacuum suit case)
- ✓ Spend much time to cathode preparation. 😞
 - Need several hours to finish preparation processes.
- Steps of NEA cathode use for actual operation in ERL
 - 1. Generate good gun vacuum, reduce backward ions...
 - 2. Establish efficient cathode change & preparation system.
 - Simultaneous several cathodes cleaning & activation.
 - Storage many activated cathodes in good vacuum.

Cathode Preparation System (2)



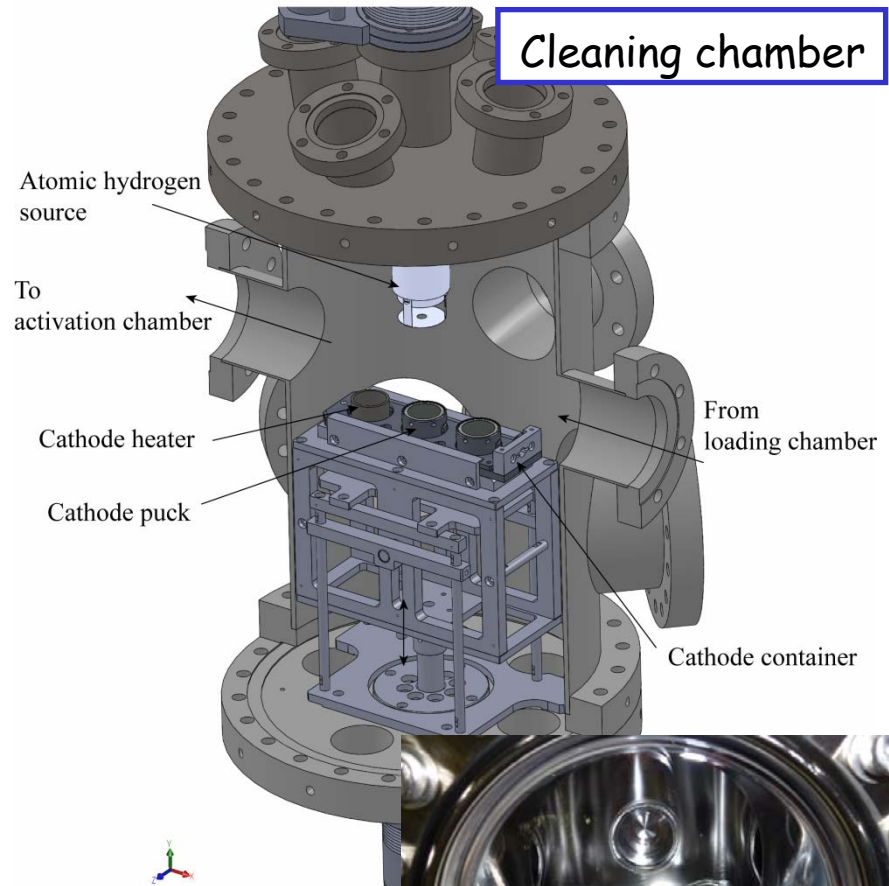
Cathode Cleaning & Activation System

Activation chamber



Three Cs sources & photo-electron collectors.
Two cathode-containers store area.

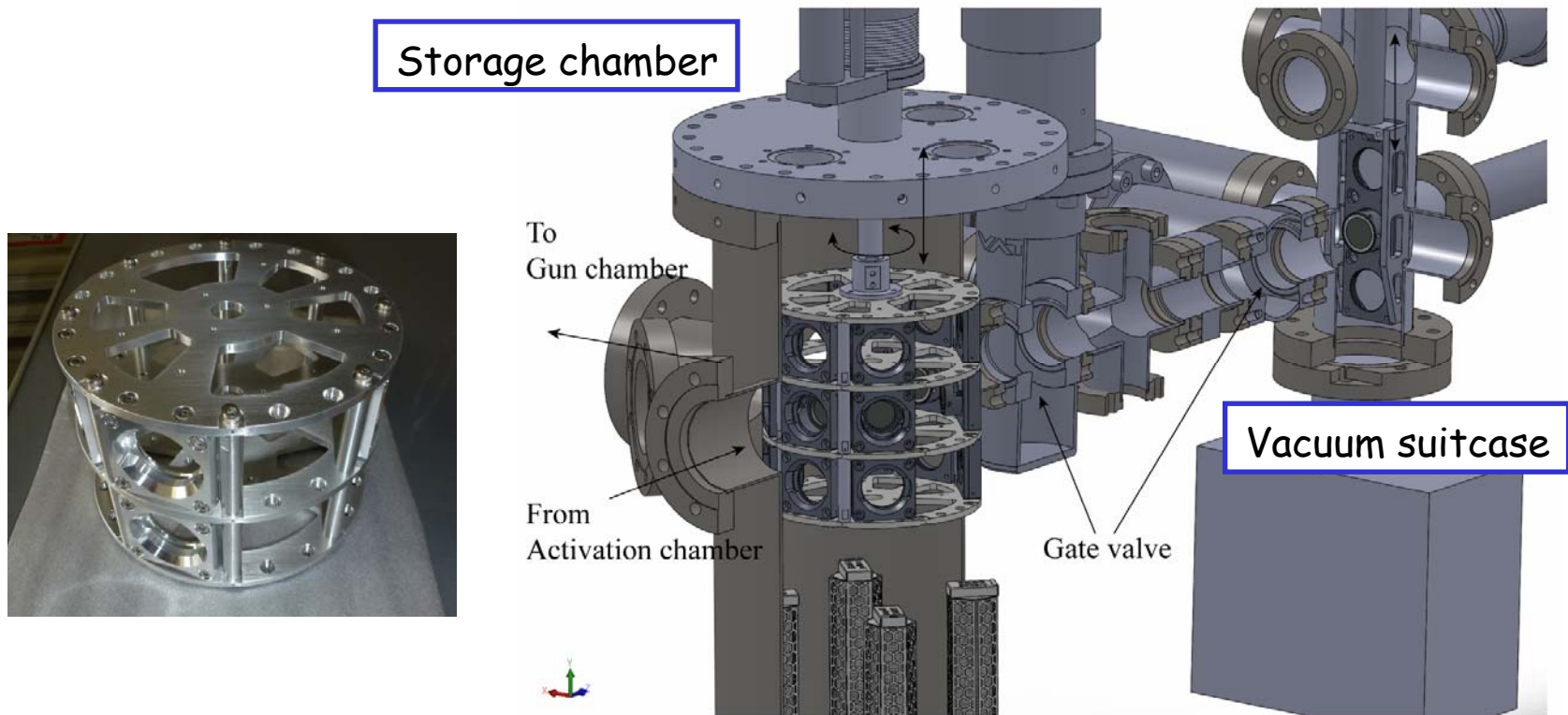
Cleaning chamber



Atomic hydrogen source(s)
& three cathode heaters



Cathode Storage & Vacuum Suitcase



- ✓ 18 cathodes (max.) can be stored under XHV condition.
- ✓ Other type of cathode can be installed directly by using vacuum suitcase optionally.
- ✓ The function of automatic QE map observation will be developed.

Summary

- ✓ The 2nd DC-gun is almost constructed.
- ✓ The total out gassing rate of overall dc gun system was suppressed to $Q \sim 8.1 \times 10^{-11}$ [Pa m³/s].
- ✓ The pumping speed of the 4K bakeable cryopump was measured.
 - ~ 1000 L/s for CH₄, N₂, CO₂ @ 1×10^{-9} [Pa].
- ✓ HV conditioning was carried out and reached over 500 kV.
 - About 90% trips happened between the anode-cathode gap.
 - 480 kV, 2 hours test has been done without HV trip.
- ✓ The design of simultaneous triplet cathodes preparation and cathode storage system has been finished. The system is now under construction.

Acknowledgement

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